

**APPARATUS AND METHOD FOR DETECTING POSITION DRIFT IN A MACHINE
OPERATION USING A ROBOT ARM**

ABSTRACT

5

Apparatus (100) for detecting position drift in a machine operation using a robot arm (114), the robot arm being for operation on a semiconductor substrate (116), the robot arm and the semiconductor substrate being configured for relative movement therebetween, the apparatus comprising: an input (102) for receiving an input signal
10 (128) from a sensor (124) mounted on the robot arm; a detector (104, 106) for detecting, from the input signal, a detection of there being a predefined distance (302) between the robot arm and the semiconductor substrate; wherein the apparatus is configured to determine, from the detection, whether there has been position drift.

15

(Fig. 1)